for the object (10,11,15) or the carrier devices (12,14).

14. Processing system according to claim 13, in which the guide surfaces (20;23) are arranged along a process line (19;22,26) which is of linear or non-linear construction.

15. Processing system according to claim 14, in which the guide surfaces (20;23) are arranged with clearance (S) to the object (10,11,15) guided along the process line (19;22;26) or the carrier device (12,14).

16. Processing system according to claim 13, in which the guide surfaces are arranged in a working space (9,17,27) located in the region of the process line (19;22;26) or adjacent to the process line (9,17,27).

17. Processing system according to claim 16, in which the working space (9,17,27) and the process line (19;22;26) are substantially on one plane.

18. Processing system according to claim 16, in which the working space (9,17,27) and the process line (19;22;26) are in different planes and the guide means (29) is aligned transversely or inclined to the plane of the process line (19;22;26).

19. Processing system according to claim 17 or 18 in which the guide surfaces (18;29) converge to each other towards an intended machining position.

20. Processing system according to one of claims 12 to 19, in which the guide means (18;20;23;29) are flexibly designed.

21. Processing system according to any of claims 12 to 20, in which the robot (1) is a mobile robot.